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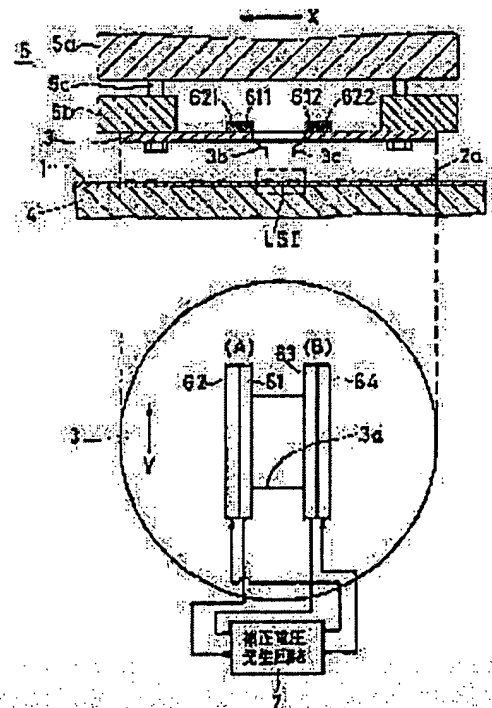
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(54) WARP CORRECTION MECHANISM FOR PROBE CARD

(57)Abstract:

PURPOSE: To obtain a mechanism for correcting a warp generated on a probe card due to the rise of inspection temperature during the inspection of an LSI tip using the probe card.

CONSTITUTION: On the probe card 3 surface, warp detection piezoelectric elements 61, 63 and warp correction piezoelectric elements 62, 64 are contacted in parallel. A correction voltage generation circuit 7 is provided to input the detection voltage detected by the warp detection piezoelectric elements and supply the bend correction piezoelectric elements with a generated correction voltage with reverse phase to the detection voltage. Thus, the warp of the probe card is corrected and the probe of the probe pin surely contacts the pad terminals corresponding to the LSI tips, and so reliable LSI tip inspection becomes possible.



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